NAPSON CORPORATION

CALTRON PTE LTD

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CRESBOX SEMI-AUTO

SHEET RESISTANCE/RESISTIVITY MEASUREMENT

CRESBOX

- Multi-point, Contact Type PC controlled via software
- 4-point probe measurement method
- User programmable measurement pattern
- Tester self-test function, small foot print
- Thickness, edge, temperature correction for silicon wafer
- Film thickness conversion function from sheet resistance
- Measure Range:
  - ✓ Resistivity: 1mΩ.cm to 300kΩ.cm
  - ✓ Sheet Resistance: 5mΩ/sq to 10MΩ/sq
- Sample Size: Ø 8”, 156mm x 156mm

APPLICABLE MATERIALS

- Semiconductor and Solar-cell materials (Silicon, Polysilicon, SiC etc)
- Functional materials (Carbon nanotube, DLC, graphene, Ag nanowire etc)
- Conductive thin film (Metal, ITO etc)
- Diffused sample (or layer)
- Silicon-related epitaxial materials, Ion-implantation sample
- Others: On Request